

Patent
Attorney's Docket No. 030681-332

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
)
Hae-seok PARK et al.) Group Art Unit: Unassigned
)
Application No.: New Application) Examiner: Unassigned
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Filed: Herewith)
)
For: MICROMIRROR ACTUATOR)

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination on the merits, kindly amend the above-captioned application as follows:

IN THE SPECIFICATION:

Kindly add the following paragraph on page 1, after the title of the invention and before the "Background of the Invention," --Priority is claimed to Patent Application number 2000-73483 filed 5 December 2001 in the Republic of Korea, herein incorporated by reference.--

Kindly replace the paragraph beginning at page 4, line 20-30 with the following:

A groove 50 is formed to a predetermined depth in the substrate 10, and an inclined contact surface 51 which will contact the lower bottom surface of the mirror 30 is formed

at one side of the groove 50. A plurality of magnets 40 are arranged at predetermined positions on the mirror 30 so that they correspond to the inclined contact surface 51.

Referring to FIG. 6, if an external magnetic field is applied to the magnets 40, the mirror 30 is rotated by a predetermined angle and then the lower bottom surface of the mirror 30 contacts the inclined contact surface 51 of the groove 50.

As long as the mirror 30 contacts the inclined contact surface 51, the mirror 30 maintains the inclination state, irrespective of additional application of an external magnetic field having a greater force to the magnets 40.

REMARKS

A few minor changes have been made to the specification by the above amendments. Favorable action on the merits is respectfully requested.

Respectfully submitted,

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Date: November 19, 2001

Attachment to Preliminary Amendment

Marked-up Copy

Page 1, Paragraph Beginning at Line 20-30

A groove 50 is formed to a predetermined depth in the substrate 10, and an inclined contact surface 51 which will contact the lower bottom surface of the mirror 30 is formed at one side of the groove 50. A plurality of magnets [51] 40 are arranged at predetermined positions on the mirror 30 so that they correspond to the inclined contact surface 51.

Referring to FIG. 6, if an external magnetic field is applied to the magnets [51] 40, the mirror 30 is rotated by a predetermined angle and then the lower bottom surface of the mirror 30 contacts the inclined contact surface 51 of the groove 50.

As long as the mirror 30 contacts the inclined contact surface 51, the mirror 30 maintains the inclination state, irrespective of additional application of an external magnetic field having a greater force to the magnets [51] 40.